

INFORMATION DISCLOSURE CITATION PTO-1449 SHEET 1 OF 2		ATTY. DOCKET NO. P121-US		SERIAL NO. 10/713,671	
		APPLICANT Dmitri Simonian, et al.			
		FILING DATE 11/13/03		GROUP Not Yet Assigned	

OIPE
 APR 27 2005
 JCS
 PATENT & TRADEMARK OFFICE

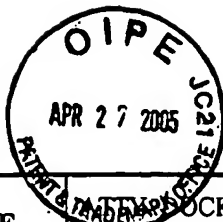
U.S. PATENT DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
BT	2003/0002019	1/2/03	Miller			
	2002/0056898	5/16/02	Lopes, et al.			
	2002/0063322	5/30/02	Robbins, et al.			
	2003/0064149	4/3/03	Miller			
	5,694,740	12/9/97	Martin, et al.			
	5,447,600	9/5/95	Webb			
	5,610,438	3/11/97	Wallace, et al.			
	5,512,374	4/30/96	Wallace, et al.			
	6,475,570	11/5/02	Jacobs			
	2004/0100677	5/27/04	Huibers, et al.			
BT	2004/0125346	7/1/04	Huibers			

FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
						<input type="checkbox"/>	<input type="checkbox"/>

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
BT	W. Robert Ashurst, et al., WAFER LEVEL ANTI-STICTION COATINGS FOR MEMS, Sensors and Actuators A 104 (2003), Pgs 213-221.
	W. Robert Ashurst et al., VAPOR PHASE ANTI-STICTION COATINGS FOR MEMS, Pgs 1-6.
	W. Robert Ashurst, et al., NANOMETER-THIN TITANIA FILMS WITH SAM-LEVEL STICKTION AND SUPERIOR WEAR RESISITANCE FOR RELIABLE MEMS PERFORMANCE, 4 pgs.
	B.C. Bunker, et al., THE IMPACT OF SOLUTION AGGLOMERATION ON THE DEPOSITION OF SELF-ASSEMBLED MONOLAYERS, 2000 American Chemical Society, Pgs 7742-7751.
	W. Robert Ashurst, et al., ALKENE BASED MONOLAYER FILMS AS ANTI-STICTION COATINGS FOR POLYSILICON MEMS, Berkeley Sensor & Actuator Center, 4 pgs.
	S Imad-Uddin Ahmed, et al., USING SELF ASSEMBLED MONOLAYERS TO REDUCE FRICTION AND WEAR IN POLYSILICON BASED MEMS, 2000, Pgs. 1-18.
BT	Uthara Srinivasan, et al., SELF ADDRESSED FLUOROCARBON FILMS FOR ENHANCED STICTION REDUCTION, 1997 ieee, Pgs. 1399-1402.

EXAMINER B. Talbot	DATE CONSIDERED 8/15/05
--------------------	-------------------------

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



INFORMATION DISCLOSURE CITATION PTO-1449 SHEET 2 OF 2		INVENTOR SOCKET NO. P121-US		SERIAL NO. Not Yet Assigned			
		APPLICANT Dima Simonian, et al.					
		FILING DATE Herewith		GROUP Not Yet Assigned			
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
BT	2004/0012838	1/22/04	Huibers				
	2004/0100594	5/27/04	Huibers, et al.				
	2004/0156090	8/12/04	Patel, et al.				
	5,835,256	11/10/98	Huibers				
	6,046,840	4/4/00	Huibers				
	6,844,959	1/18/05	Huibers, et al.				
	6,867,897	3/15/05	Patel, et al.				
	5,287,096	2/15/94	Thompson, et al.				
	6,204,085	3/20/01	Strumpell, et al.				
	6,300,294	10/9/01	Robbins, et al.				
BT	6,086,726	7/11/00	Renk, et al.				
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
						<input type="checkbox"/>	<input type="checkbox"/>
						<input type="checkbox"/>	<input type="checkbox"/>
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
EXAMINER B. Talbot			DATE CONSIDERED 8/15/05				

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line thro

INFORMATION DISCLOSURE CITATION PTO-1449		ATTY. DOCKET NO.		SERIAL NO.			
		P121-US		Not Yet Assigned			
		APPLICANT Dima Simonia					
		FILING DATE Herewith		GROUP Not Yet Assigned			
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
BT	6,300,294	10/09/01	Robbins, et al.				
	6,259,551	07/10/01	Jabobs				
I	5,936,758	08/10/99	Fisher, et al.				
	5,411,769	05/02/95	Hornbeck				
BT	5,939,785	08/17/99	Klonis, et al.				
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
						<input type="checkbox"/>	<input type="checkbox"/>
						<input type="checkbox"/>	<input type="checkbox"/>
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
BT	Uthara Srinivasan, et al., ALKYLTRICHLOROSILANE-BASED SELF-ASSEMBLED MONOLAYER FILMS FOR STRICTION REDUCTION IN SILICON MICROMACHINES., Journal of Microelectromechanical Systems, Vol. 7, No. 2 June 1998, Pgs 252-260.						
	H. Zarrad, et al., OPTIMIZATION OF LUBRICANTS FOR SILICA MICROMOTORS., Sensors and Actuators A 46-47 (1995), Pgs 598-600.						
I	Uthara Srinivasan, et al., 1997 INTERNATIONAL CONFERENCE ON SOLID-STATE SENSORS AND ACTUATORS., Transducers 97 Chicago, June 16-19, 1997.						
	Roya Maboudian, et al., STRICTION REDUCTION PROCESSES FOR SURFACE MICROMACHINES., Tribology Letters 3 (1997), Pgs 215-221.						
I	K. Komvopoulos, SURFACE ENGINEERING AND MICROTRIBOLOGY FOR MICROELECTROMECHANICAL SYSTEMS., Wear 200 (1996), Pgs 305-327.						
	W. Robert Ashurst, WAFER LEVEL ANTI-STICTION COATINGS FOR MEMS., Sensors and Actuators A 104 (2003), Pgs 213-221.						
BT	H. Zarrad, et al., THE USE OF LONG-CHAIN MOLECULES FOR THE LUBRICATION OF MICROMECHANISMS., Journal of Micromech. Microeng. 3 (1993), Pgs 222-224.						
EXAMINER		BTalbot		DATE CONSIDERED		8/15/05	

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

